# Vertical Bloch Line (VBL) Storage Technology

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# VBL Technology Presentation Overview

- A Solid-State Storage Myth
- Technology Attributes
- ☐ Technology Architecture
- Technology Status

#### The solid-state storage myth

- ☐ The myth: Providing solid-state storage must <u>always</u> be expensive:
  - It is often assumed that solid-state storage must be expensive on a per-bit basis.
  - •It is often assumed that mechanical technologies, such as disk and tape, must be less expensive.
- ☐ The basis for the myth:
  - Alternative (non-VBL) solid-state technologies are often costly:
    - -Fabrication processes are often costly/exotic.
    - -Yields are low.
  - Alternative solid-state technologies often offer low performance:
    - —Low chip capacities (64 kbits-1 Mbit).
    - —Performance limitations:
      - O Poor reliability.
      - O Slow write/erase rates.
      - O Limited cyclability.
      - Other limitations.
  - . Thus high cost per bit and reduced marketcompetitiveness often result.

### VBL technology opportunity against the solid-state storage myth

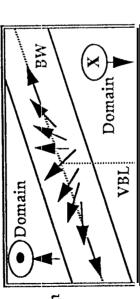
- VBL technologyopportunity:
  - VBL technology has inherent attributes that can make it less expensive to produce than today's DRAM, disk, and tape costs:
    - —High bit density.
    - —Low fabrication costs:
      - O Simple and high-yield fabrication processes.
      - O Simple and high-yield device design structures.
      - O Standard Czochralski substrate wafer growth.
- ☐ Achieving functionality at high volume and high yield is the key.

#### VBL Technical Background Technology Opportunity

- □ VBL technology Potential uniquely and simultaneously offers many desirable data storage attributes in a single technology:
  - High areal storage density: >1 Gbit per chip.
  - Hi g volumetric storage density: 1 Gbit/cm³ to >1 Tbit/cm³.
  - . So Id-state form.
  - Nonvolatility.
  - Radiation hardness.
  - Scalability for future technology advancement.
  - Dual-usability.
  - Mass data erasability.
  - No material fatigue limitations.
  - Near-term availability.
- ☐ VBL capabilities can enable new data system concepts and applications:
  - SolId-State Recorders
  - . Solid-State Disks
  - Local storage for processor nodes
  - Buffer Storage
  - Archival storage

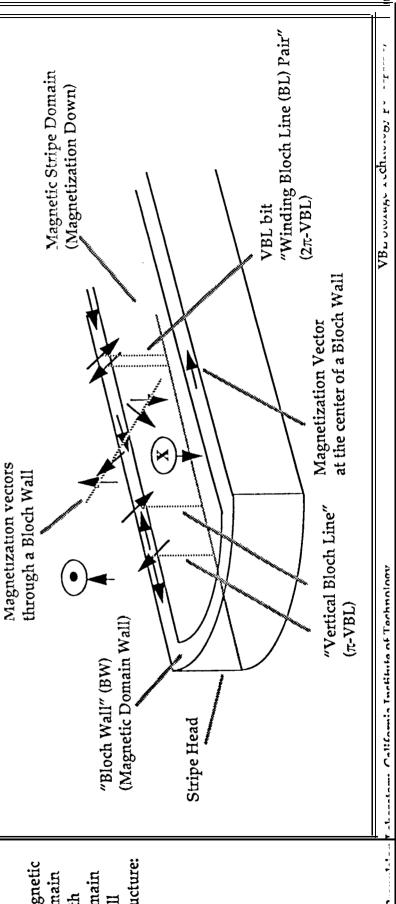
# Magnet'c Domain Structure: Background

magnetization a Bloch Wall. Bloch Line in through a Close-up vectors of the



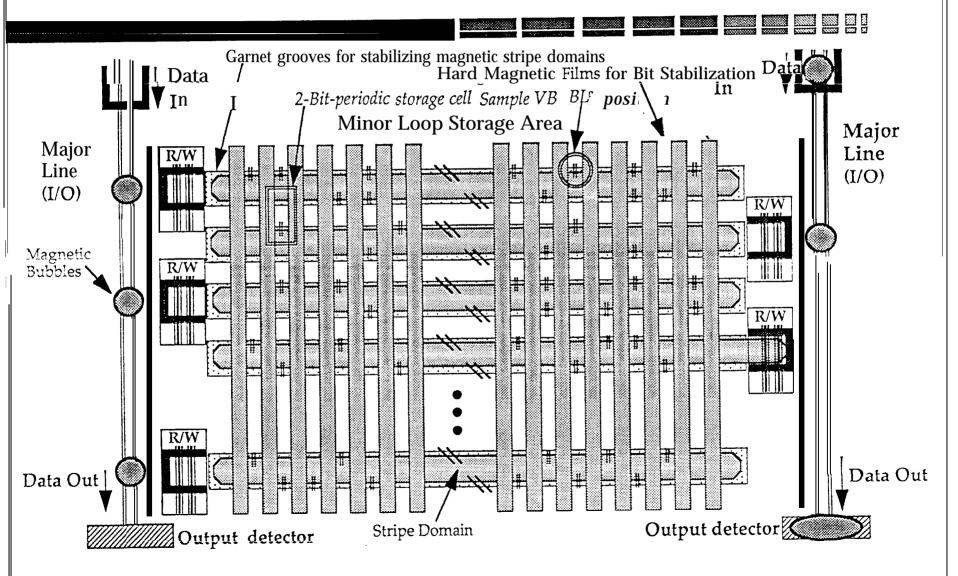
Energy density, Bloch Wall w/ periodic array of BLs:  $\sigma_* = \sigma_0 [1 + (\pi \Delta_0/s)^2 + (2Q)^{-1}]^{1/2}$ Thickness, BW w/ periodic array (s) of BLs=  $\Delta_* = \Delta_0 [1 + (\pi \Delta_0/s)^2 + (2Q)^{-1}]^{-1/2}$ A=Exchange constant; K\_=Perpendicular anisotropy constant;  $K_p$ =In-plane anisotropy constant M=Magnetization. Thickness, straight BW =  $\Delta_0 = \pi (\Lambda/K_u)^{1/2}$ Energy density, straight BW =  $\sigma_0$ =4(AK<sub>u</sub>)<sup>1/2</sup> Thickness, single BL:  $\pi(A/12\pi \hat{M}^2\pm K_p\,|\,)^{1/2}$  $Q=K_u/2\pi M^2$ 

> magnetic structure: domain domain with



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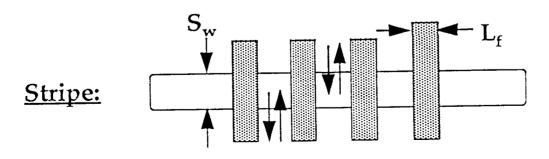
#### A VBL Storage Chip Architecture



# VBL Storage Chips: Areal Storage Density Performance

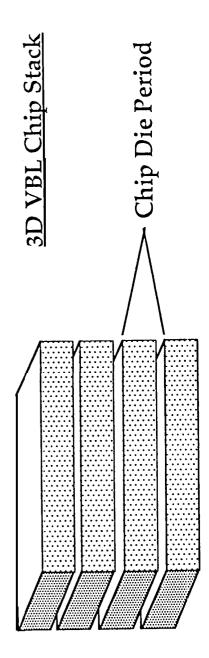
	$\underline{L}_{\underline{f}} = 1  \mu \underline{m}$	$\underline{L}_{\underline{f}} = 0.5  \mu \underline{m}$	$\underline{L}_{\underline{f}} = 0.1 \text{ urn}$
$S^*=5 \mu m$ $S^*=2 \mu m$ $S_w=1 \mu m$ $S_w=0.5 urn$ $S_w=0.25 \mu m$	10 Mbits/cm <sup>z</sup> 25 Mbits/cm <sup>z</sup> 50 Mbits/cm <sup>z</sup> 100 Mbits/cm <sup>z</sup> 200 Mbits/cm*	20 Mbits/cm <sup>2</sup> 50 Mbits/cm <sup>2</sup> 100 Mbits/cm <sup>2</sup> 200 Mbits/cm <sup>2</sup> 400 Mbits/cm <sup>2</sup>	100 Mbits/cm <sup>2</sup> 250 Mbits/cm <sup>2</sup> 500 Mbits/cm <sup>2</sup> 1,000 Mbits/cm <sup>2</sup> 2,000 Mbits/cm <sup>2</sup>

#### VBL Memory areal storage density is proportional to: $1/((s_r)_x(L_f))$

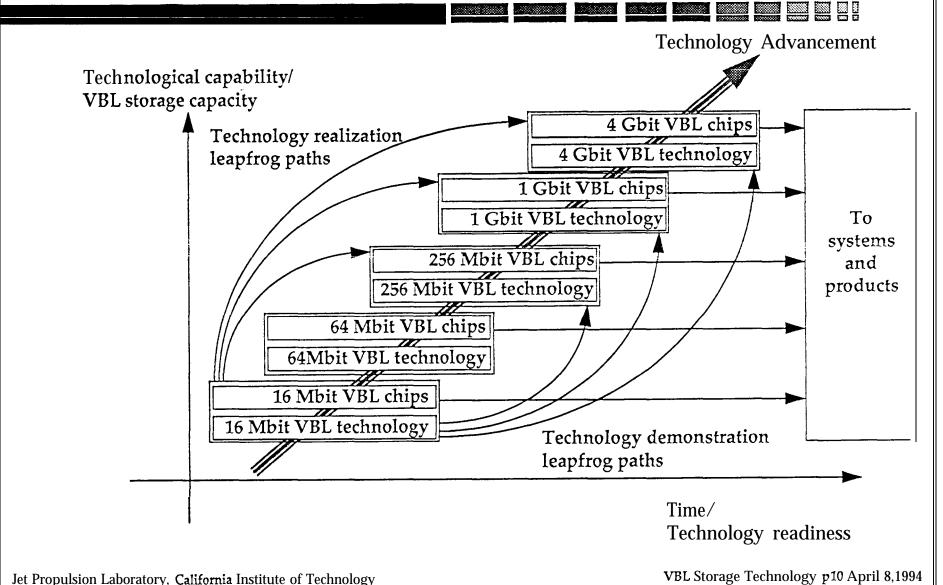


# VBL Storage Chips: Volumetri= Storage Performance

Areal Storage Density 25 Mbits/cm <sup>2</sup> 200 Mbits/cm <sup>2</sup>	16 die/cm (25 mils/die) (625 µm/die) 0.4 Gbits/cc 3.2 Gbits/cc 3.2 Gbits/cc	40 die/cm (10 mils/die) (250 µm/die) 1 Gbit/cc 4 Gbits/cc 8 Gbits/cc	chin Die Deneity e/cm 200 die/cm [s/die) (2 mils/die) n/die) (50 µm/die) it/cc 5 Gbits/cc its/cc 20 Gbits/ee its/cc 40 Gbits/ee	400 die/cm (1 mil/die) (25 µm/die) 10 Gbits/cc 40 Gbits/cc 80 Gbits/cc
$1,000 \text{ Mbits/cm}^2$ $1 \stackrel{<}{\circ} \infty 0 \text{ Mbits/cm}^2$		40 Gbits/cc 4∞ Gbits/cc	200 Gbits/cc 2,∞ Gbits/cc	400 Gbits/cc



### VBL Technology Advancement Path



# VBL Technology Near Term Development Goals

- Solid-state, nonvolatile chips:
  - •16 Mbits, 64 Mbits, and/or 256 Mbit chips.
  - 2 Gbits per cubic centimeter in 3D packaging.
  - 300 Gbits per kg in 3D packaging.
- ☐ Data rates:
  - 0 to >40 Mbit/sec per chip.
  - >1 Gbit/sec per system.
- Power consumption:
  - < 10 mW per Mbit/see during input/output operations.
  - < YU m'w peractive chip during bit propagation operations.
- ☐ Applicability:
  - Ruggedizable.
  - Space qualifiable.
  - Commercializable.

#### Potential VBL Production Cost Advantage

- ☐ VBL tennology can be cheaper to produce per bit than any present IC technology:
  - Wafer fabrication costs can be lower.
  - Substrate fabrication costs reduce with volume applications.
- VBL comparisons to semiconductor processing:
  - VBL has no pn junction issues:
    - —VBL is less sensitive to contamination.
    - —VBL is less sensitive to impurities.
  - VBL has no interlayer contacts (vias) in the memory storage array.
  - VBL has no polysilicon and no gate oxide (big CMOS issues).
  - VBL fabrication requires no special processing equipment.
  - Lithography:
    - —VBL has more bits/cm² with the same design rules.
    - —Bit density more tolerant to alignment errors.
    - —Long, parallel lines ideal for future x-ray and holographic lithography.
  - VBL has fewer mask steps than CMOS.
  - VBL energy stored per bit stays constant as bit size shrinks.

#### VBL Technology Status

- ☐ Features which have been demonstrated:
  - Bubble propagation in the major line.
  - Stripe chopping for readback.
  - Stripe expansion for writing.
  - Partial grooving stripe stabilization.
  - Permanent magnet bit cell formation
  - Ability to match bias fields in chip to realize a single chip operating point.
  - VBL observability.
  - Computer simulation capabilities.
- **■** Features to be demonstrated:
  - A fully integrated storage device with good margins, including:
    - —Integrated write/read gates.
    - —Integrated input/output data line with signal detector.
    - —Active bit definition.
- **Features** needing demonstration:
  - Storage density upper limits.
  - Maximum data access and transfer rates.
  - Minimum power performance.

#### VBL Conclusions

- VBL technology potentially offers a variety of desirable data storage technology attributes for a variety of applications.
- □ VBL technology potentially offers high market volume and effective cost performance potential.
- Near-term development plans are intended to develop VBL technology to realize technological potential.